

PATENT
30205/37916

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Jae Hong Kim and
 Sang Ick Lee

Serial No.: 10/038,375

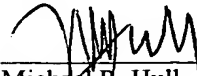
Filed: January 4, 2002

For: Chemical Mechanical Polishing
 Slurry and Process for Ruthenium Films

Group Art Unit: 2829

Examiner: Asok K. Sarkar

) I hereby certify that this paper and the
) documents referred to as enclosed
) therewith are being deposited with the
) United States Postal Service as first class
) mail, postage prepaid, on November 26,
) 2003, in an envelope addressed to
) Commissioner for Patents, P.O. Box
) 1450, Alexandria, Virginia 22313-1450


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AMENDMENT

Commissioner for Patents
 P.O. Box 1450
 Alexandria, Virginia 22313-1450

Sir:

In response to the office action mailed on August 27, 2003, please amend the
 above-referenced patent application as follows.

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